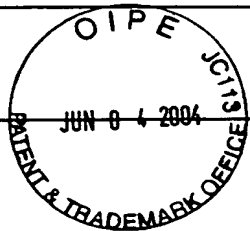


JFW



U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICE

**SUPPLEMENTAL INFORMATION
DISCLOSURE STATEMENT**

Docket Number
10020/29701

Application Number
10/690,704

Filing Date
October 23, 2003

Examiner
Not Yet Assigned

Art Unit
1762

Invention Title
**METHOD AND APPARATUS FOR
DEPOSITING MATERIAL**

Inventor(s)
SHTEIN et al.

Address to:
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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Date: 6/2/04

Signature: Thomas F. Meagher

Thomas F. Meagher (Reg. No. 29,831)

1. In accordance with the duty of disclosure under 37 C.F.R. § 1.56 and in conformance with the procedures of 37 C.F.R. §§ 1.97 and 1.98 and M.P.E.P. § 609, attorneys for Applicants hereby bring the following references to the attention of the Examiner. The references are listed on the attached modified PTO Form No. 1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the references be made of record therein and appear among the "References Cited" on any patent to issue therefrom.
2. A copy of each patent, publication or other information listed on the modified PTO form 1449 is enclosed, unless otherwise indicated.
3. It is believed that no fees are due in connection with this Information Disclosure Statement. However, should any fees be due, the Commissioner is authorized to charge Deposit Account No. 11-0600 for such fees. A copy of this communication is enclosed for charging purposes.

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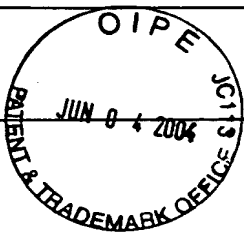
By: Thomas F. Meagher

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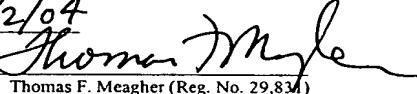
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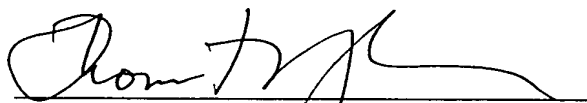
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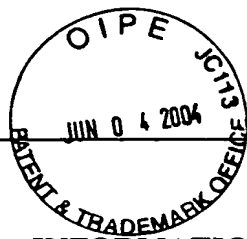
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**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT
PTO-1449**

DOCKET NO.
10020/29701

SERIAL NO.
10/690,704

APPLICANT
SHTEIN et al.

FILING DATE
October 23, 2003

GROUP
1762

U. S. PATENT DOCUMENTS

EXAMINER INITIAL	PATENT NUMBER	PATENT DATE	NAME	CLASS	SUBCLASS	FILING DATE*
	4,788,082	November 29, 1988	Schmitt			
	5,256,205	October 26, 1993	Schmitt, III et al.			
	5,650,197	July 22, 1997	Halpern			

FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
						YES	NO

OTHER DOCUMENTS

EXAMINER INITIAL		AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.
		A.K. Rebrov, "Free Jets in Vacuum technologies", J. Vac. Sci. Technol., A 19(4), pp. 1679-1687, Jul/Aug 2001.
		J. Fernandez de la Mora, "Surface impact of seeded jets at relatively large background densities", J. Chem. Phys, 82 (7), pp. 3453-3464, April 1, 1985.
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		Zhang et al., "Jet Vapor Deposition of Organic Guest-Inorganic Host Thin Films for Optical and Electronic Applications", Journal of Electronic Materials, Volume 23, No. 11, pp. 1239-1244, Nov. 1994.

EXAMINER	DATE CONSIDERED
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	